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APPLICATION NO.	I	FILING DATE	FIRST NAMED INVENTOR	ATTORNEY DOCKET NO.	CONFIRMATION NO.	
10/747,613 12/30/2003		Vadim Yevgenyevich Banine	081468-0307456	2894		
909	7590	02/10/2005	EXAMINER			
		ΓHROP, LLP	RUTLEDGE, DELLA J			
P.O. BOX 10500 MCLEAN, VA 22102				ART UNIT	PAPER NUMBER	
ŕ				2851		
	·			DATE MAILED: 02/10/2005		

Please find below and/or attached an Office communication concerning this application or proceeding.

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	Application No.	Applicant(s)					
	10/747,613	BANINE ET AL.					
Office Action Summary	Examiner	Art Unit	-				
	D. Rutledge	2851					
The MAILING DATE of this communication a Period for Reply	ppears on the cover sheet with the o	correspondence address					
A SHORTENED STATUTORY PERIOD FOR REF THE MAILING DATE OF THIS COMMUNICATION - Extensions of time may be available under the provisions of 37 CFR after SIX (6) MONTHS from the mailing date of this communication. - If the period for reply specified above is less than thirty (30) days, a r - If NO period for reply is specified above, the maximum statutory perion - Failure to reply within the set or extended period for reply will, by state Any reply received by the Office later than three months after the material earned patent term adjustment. See 37 CFR 1.704(b).	N. 1.136(a). In no event, however, may a reply be tirely within the statutory minimum of thirty (30) day of will apply and will expire SIX (6) MONTHS from tute, cause the application to become ABANDONE	nely filed rs will be considered timely. the mailing date of this communication. D (35 U.S.C. § 133).					
Status							
1) Responsive to communication(s) filed on	<u></u> .	•					
2a) This action is FINAL . 2b) ⊠ The	nis action is non-final.						
3) Since this application is in condition for allow) Since this application is in condition for allowance except for formal matters, prosecution as to the merit						
closed in accordance with the practice under Ex parte Quayle, 1935 C.D. 11, 453 O.G. 213.							
Disposition of Claims							
4) ☐ Claim(s) 1-20 is/are pending in the application 4a) Of the above claim(s) is/are withden 5) ☐ Claim(s) is/are allowed. 6) ☐ Claim(s) 1-5.7.10-14,19,20 is/are rejected. 7) ☐ Claim(s) 6,8,9 and 15-18 is/are objected to. 8) ☐ Claim(s) are subject to restriction and	rawn from consideration.						
Application Papers							
9) The specification is objected to by the Exami							
10)☐ The drawing(s) filed on is/are: a)☐ a	ccepted or b) \square objected to by the \square	Examiner.					
Applicant may not request that any objection to the							
Replacement drawing sheet(s) including the correct 11) The oath or declaration is objected to by the	· · · · · · · · · · · · · · · · · · ·						
Priority under 35 U.S.C. § 119							
12) Acknowledgment is made of a claim for foreign a) All b) Some * c) None of: 1. Certified copies of the priority docume 2. Certified copies of the priority docume 3. Copies of the certified copies of the prapplication from the International Bure * See the attached detailed Office action for a li	ents have been received. Ents have been received in Applicationity documents have been received and (PCT Rule 17.2(a)).	on No ed in this National Stage					
Attachment(s)	_						
1) Notice of References Cited (PTO-892) 2) Notice of Draftsperson's Patent Drawing Review (PTO-948)	4) Interview Summary Paper No(s)/Mail Da	· ·					
 Notice of Draftsperson's Patent Drawing Review (P10-948) Information Disclosure Statement(s) (PTO-1449 or PTO/SB/0 Paper No(s)/Mail Date <u>07/04 & 01/05</u>. 		Patent Application (PTO-152)					
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DETAILED ACTION

Claim Rejections - 35 USC § 103

- 1. The following is a quotation of 35 U.S.C. 103(a) which forms the basis for all obviousness rejections set forth in this Office action:
 - (a) A patent may not be obtained though the invention is not identically disclosed or described as set forth in section 102 of this title, if the differences between the subject matter sought to be patented and the prior art are such that the subject matter as a whole would have been obvious at the time the invention was made to a person having ordinary skill in the art to which said subject matter pertains. Patentability shall not be negatived by the manner in which the invention was made.
- 2. This application currently names joint inventors. In considering patentability of the claims under 35 U.S.C. 103(a), the examiner presumes that the subject matter of the various claims was commonly owned at the time any inventions covered therein were made absent any evidence to the contrary. Applicant is advised of the obligation under 37 CFR 1.56 to point out the inventor and invention dates of each claim that was not commonly owned at the time a later invention was made in order for the examiner to consider the applicability of 35 U.S.C. 103(c) and potential 35 U.S.C. 102(e), (f) or (g) prior art under 35 U.S.C. 103(a).
- 3. Claims 1 5, 7, 10, 11 14, 19 and 20 are rejected under 35 U.S.C. 103(a) as being unpatentable over Flora et al. (EP 1 211 918) in view of Reid (US 6,589,354). Flora et al. have a system and method of mitigating debris particles in a lithographic apparatus. The apparatus has an illumination structure comprising a laser that produces a EUV plasma source, a support for a reflective mask and a support for the wafer. See the embodiments in Figs. 5 9. The mitigating system has a non-ionized gas source, krypton, which interacts with the contaminant particles and ions to mitigate them. Particle generation forms part of the radiation source. One of ordinary skill in the

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art would have known that that there are other means of generating plasma and would have used Radio Frequency induction coils if they provides a more economic or space saving feature.

Reid teaches that an ionized gas will neutralize the electrostatic attraction of ionized contaminants and dislodge the contaminants from a surface. The flow of the additional particles is different from the direction of the contaminants and the direction of the radiation beam. The arrangement uses ionized gas 140, ducts provide an outlet and a collector 115 of the particles, while the exhaust pump, etc. serve to control the flow of the particles 150. One of ordinary skill in the art at the time the invention was made would be motivated to ionize the krypton gas to enhance the mitigation of the debris particles.

Allowable Subject Matter

- 4. Claims 6, 8, 9, and 15 18 are objected to as being dependent upon a rejected base claim, but would be allowable if rewritten in independent form including all of the limitations of the base claim and any intervening claims.
- 5. The following is a statement of reasons for the indication of allowable subject matter: The prior does not suggest or teach supersonic flow of the additional particles; nor provide a plurality of electrodes as claimed.

Response Data

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Any inquiry concerning this communication or earlier communications from the examiner should be directed to D. Rutledge whose telephone number is (571) 272-2127. The examiner can normally be reached on Mon - Thurs, 6:00 AM - 4:30 PM.

If attempts to reach the examiner by telephone are unsuccessful, the examiner's supervisor, Judy Nguyen can be reached on (571) 272-2258. The fax phone number for the organization where this application or proceeding is assigned is 703-872-9306.

Information regarding the status of an application may be obtained from the Patent Application Information Retrieval (PAIR) system. Status information for published applications may be obtained from either Private PAIR or Public PAIR. Status information for unpublished applications is available through Private PAIR only. For more information about the PAIR system, see http://pair-direct.uspto.gov. Should you have questions on access to the Private PAIR system, contact the Electronic Business Center (EBC) at 866-217-9197 (toll-free).

D. Rutledge Primary Examiner Art Unit 2851

dr 2/7/05